J-L Deschanvres

List of Publications by Year
in descending order

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72 papers	1,072 citations	430874 18 h-index	501196 28 g-index
72 all docs	72 docs citations	72 times ranked	1357 citing authors

#	Article	IF	Citations
1	ZnO/CuCrO₂ Coreâ€“Shell Nanowire Heterostructures for Selfâ€Powered UV Photodetectors with Fast Response. Advanced Functional Materials, 2018, 28, 1803142.	14.9	75
2	Thin films of high-resistivity zinc oxide produced by a modified CVD method. Thin Solid Films, 1992, 213, 94-98.	1.8	61
3	Deposition of ZnO based thin films by atmospheric pressure spatial atomic layer deposition for application in solar cells. Journal of Renewable and Sustainable Energy, 2017, 9, .	2.0	51
4	Characterization of piezoelectric properties of zinc oxide thin films deposited on silicon for sensors applications. Sensors and Actuators A: Physical, 1992, 33, 43-45.	4.1	50
5	Efficient green and red up-conversion emissions in Er/Yb co-doped TiO 2 nanopowders prepared by hydrothermal-assisted solâ€gel process. Journal of Luminescence, 2016, 176, 250-259.	3.1	48
6	Preparation of nanocrystalline titania powder via aerosol pyrolysis of titanium tetrabutoxide. Journal of Materials Research, 1999, 14, 3938-3948.	2.6	44
7	Aerosol synthesis of Tiâ€“O powders via in-droplet hydrolysis of titanium alkoxide. Materials Science & Engineering A: Structural Materials: Properties, Microstructure and Processing, 2001, 315, 113-121.	5.6	33
8	Growth and characterization of Sr-doped Cu₂O thin films deposited by metalorganic chemical vapor deposition. Physica Status Solidi (A) Applications and Materials Science, 2015, 212, 1735-1741.	1.8	33
9	Evolution of Crystal Structure During the Initial Stages of ZnO Atomic Layer Deposition. Chemistry of Materials, 2016, 28, 592-600.	6.7	31
10	Influence of physico-structural properties on the photocatalytic activity of sol-gel derived TiO2 thin films. Journal of Materials Science, 2006, 41, 2915-2927.	3.7	29
11	SIRIUS: A new beamline for in situ X-ray diffraction and spectroscopy studies of advanced materials and nanostructures at the SOLEIL Synchrotron. Thin Solid Films, 2016, 617, 48-54.	1.8	28
12	Crystal field analysis of erbium doped yttrium oxide thin films inC2 andC3i sites. Physica Status Solidi (B): Basic Research, 2003, 239, 193-202.	1.5	25
13	SnO2 Films Deposited by Ultrasonic Spray Pyrolysis: Influence of Al Incorporation on the Properties. Molecules, 2019, 24, 2797.	3.8	25
14	Magnesiumâ€doped cuprous oxide (Mg:Cu₂O) thin films as a transparent pâ€type semiconductor. Physica Status Solidi (A) Applications and Materials Science, 2016, 213, 2296-2302.	1.8	24
15	Use of cerium ethylhexanoate solutions for preparation of CeO2 buffer layers by spin coating. Materials Science and Engineering B: Solid-State Materials for Advanced Technology, 2003, 104, 185-191.	3.5	22
16	Structural and luminescence correlation of annealed Er-ZnO/Si thin films deposited by AACVD process. Materials Science and Engineering B: Solid-State Materials for Advanced Technology, 2013, 178, 1124-1129.	3.5	22
17	Antireflective downconversion ZnO:Er3+,Yb3+ thin film for Si solar cell applications. Journal of Applied Physics, 2015, 117, .	2.5	22
18	In-situ Raman spectroscopy and X-ray diffraction studies of the structural transformations leading to the SrCu2O2 phase from strontiumâ€“copper oxide thin films deposited by metalorganic chemical vapor deposition. Thin Solid Films, 2013, 541, 136-141.	1.8	19

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19	Deposition of TiO2 thin films by atmospheric plasma post-discharge assisted injection MOCVD. Surface and Coatings Technology, 2007, 201, 8971-8975.	4.8	17
20	Thermal annealing of amorphous Tiâ€“Siâ€“O thin films. Journal of Materials Research, 2008, 23, 755-759.	2.6	17
21	Out of stoichiometry CuCrO₂ films as a promising p-type TCO for transparent electronics. Materials Advances, 0, , .	5.4	17
22	High Tc superconducting films obtained by pyrolysis of an ultrasonically deposited gel. Thin Solid Films, 1989, 174, 263-268.	1.8	16
23	New spray pyrolysis deposition and magnetic properties of ferrite thin films for microwave applications. Journal of Magnetism and Magnetic Materials, 1990, 83, 437-438.	2.3	16
24	Effect of Humidity and UV Assistance on the Properties of Erbium Doped Yttrium Oxide Films Prepared by Aerosol-MOCVD. Chemical Vapor Deposition, 2011, 17, 93-97.	1.3	16
25	Highly efficient NIR to visible upconversion in a ZnO:Er,Yb thin film deposited by a AACVD atmospheric pressure process. RSC Advances, 2015, 5, 60246-60253.	3.6	15
26	Tuning the properties of F:SnO₂ (FTO) nanocomposites with S:TiO₂ nanoparticles â€“ promising hazy transparent electrodes for photovoltaics applications. Journal of Materials Chemistry C, 2017, 5, 91-102.	5.5	15
27	Thulium and Ytterbium-Doped Titanium Oxide Thin Films Deposited by Ultrasonic Spray Pyrolysis. Journal of Thermal Spray Technology, 2012, 21, 1263-1268.	3.1	14
28	An Atomistic View of the Incipient Growth of Zinc Oxide Nanolayers. Crystal Growth and Design, 2016, 16, 5339-5348.	3.0	14
29	Effect of Strontium Incorporation on the p-Type Conductivity of Cu₂O Thin Films Deposited by Metalâ€“Organic Chemical Vapor Deposition. Journal of Physical Chemistry C, 2016, 120, 17261-17267.	3.1	14
30	Study of the growth and annealing conditions of SrCu2O2(SCO) thin films deposited by injection MOCVD. Physica Status Solidi (A) Applications and Materials Science, 2008, 205, 2013-2017.	1.8	13
31	Influence of deposition conditions on the optical properties of erbium-doped yttrium oxide films grown by aerosolâ€“UV assisted MOCVD. Journal of Luminescence, 2011, 131, 2311-2316.	3.1	13
32	Efficient antireflective downconversion Er3+ doped ZnO/Si thin film. Physics Letters, Section A: General, Atomic and Solid State Physics, 2014, 378, 1733-1738.	2.1	13
33	Density, thickness and composition measurements of TiO2SiO2 thin films by coupling X-ray reflectometry, ellipsometry and electron probe microanalysis-X. Applied Surface Science, 2006, 253, 363-366.	6.1	11
34	The initial stages of ZnO atomic layer deposition on atomically flat In_{0.53}Ga_{0.47}As substrates. Nanoscale, 2018, 10, 11585-11596.	5.6	11
35	Resilience of Cuprous Oxide under Oxidizing Thermal Treatments via Magnesium Doping. Journal of Physical Chemistry C, 2019, 123, 8663-8670.	3.1	11
36	The effect of rare earth element (Er, Yb) doping and heat treatment on suspension stability of Y2O3 nanoparticles elaborated by sol-gel method. Journal of Materials Research and Technology, 2020, 9, 12634-12642.	5.8	11

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37	Garnet thin film deposited by a new chemical vapour deposition. Thin Solid Films, 1989, 175, 281-285.	1.8	10
38	Growth of garnet thin films for magneto-optic memories by pyrosol CVD process. IEEE Transactions on Magnetics, 1990, 26, 187-189.	2.1	10
39	Optical and crystal-field analysis of Er3+ ion in Y2O3â€“P2O5 thin films. Journal of Luminescence, 2007, 126, 165-170.	3.1	10
40	Growth and characterisation of CaCu2Ox thin films by pulsed injection MOCVD. Thin Solid Films, 2008, 516, 1461-1463.	1.8	10
41	Efficient upconversion in Er3+ doped Y2O3/Si thin film deposited by aerosol UV-assisted MOCVD process. Journal of Luminescence, 2016, 170, 231-239.	3.1	9
42	Cu₂O Thin Films: The Role of Humidity in Tuning the Texture and Electrical Properties of Cu₂O Thin Films Deposited via Aerosolâ€Assisted CVD (Adv. Mater. Interfaces 3/2019). Advanced Materials Interfaces, 2019, 6, 1970020.	3.7	9
43	Structural study of TiO₂hierarchical microflowers grown by aerosol-assisted MOCVD. CrystEngComm, 2017, 19, 1535-1544.	2.6	8
44	Growth of Amorphous Tiâ€“Siâ€“O Thin Films by Aerosol CVD Process at Atmospheric Pressure. Journal of the Electrochemical Society, 2008, 155, D110.	2.9	7
45	In situ x-ray studies of the incipient ZnO atomic layer deposition on <mml:math xmlns:mml="http://www.w3.org/1998/Math/MathML"><mml:mrow><mml:msub><mml:mi>In</mml:mi><mml:mrow><mml:mn>0.53</mml:mn> Physical Review Materials, 2020, 4, .	2.4	7
46	Direct bonding conditions of ferrite garnet layer on ionâ€exchanged glass waveguides. Physica Status Solidi (A) Applications and Materials Science, 2008, 205, 2313-2316.	1.8	6
47	Growth of lanthanide-doped YF3 thin films by pulsed liquid injection MOCVD: Influence of deposition parameters on film microstructure. Surface and Coatings Technology, 2013, 230, 22-27.	4.8	6
48	Evaluation of Alternative Atomistic Models for the Incipient Growth of ZnO by Atomic Layer Deposition. Journal of Electronic Materials, 2017, 46, 3512-3517.	2.2	6
49	The Effect of Solvents and Rare-Earth Element (Er, Yb) Doping on Suspension Stability of Solâ€“Gel Titania Nanoparticles. IEEE Transactions on Nanobioscience, 2017, 16, 718-726.	3.3	6
50	Marine Antibiofouling Properties of TiO2 and Ti-Cu-O Films Deposited by Aerosol-Assisted Chemical Vapor Deposition. Coatings, 2020, 10, 779.	2.6	6
51	In Situ Ellipsometry Study of the Early Stage of ZnO Atomic Layer Deposition on In 0.53 Ga 0.47 As. Physica Status Solidi (A) Applications and Materials Science, 2020, 217, 1900831.	1.8	6
52	In situ ellipsometry monitoring of TiO2 atomic layer deposition from Tetrakis(dimethylamido)titanium(IV) and H2O precursors on Si and In0.53Ga0.47As substrates. Thin Solid Films, 2021, 723, 138591.	1.8	5
53	Grain-boundary segregation of magnesium in doped cuprous oxide and impact on electrical transport properties. Scientific Reports, 2021, 11, 7788.	3.3	5
54	Growth of Bi-substituted YIG thin films for magneto-optic applications. Journal of Magnetism and Magnetic Materials, 1991, 101, 224-226.	2.3	4

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55	Effect of thermal annealing on electrical and optical properties of Ba-doped SrCu2 O2 thin films on glass substrates. Physica Status Solidi (A) Applications and Materials Science, 2013, 210, 2569-2574.	1.8	4
56	Antireflection and downconversion response of Nd3+ doped Y2O3/Si thin film deposited by AACVD process. Chemical Physics Letters, 2014, 612, 1-7.	2.6	4
57	Growth and Properties of Amorphous Erbiumâ€doped Aluminumâ€yttrium Oxide Films Deposited by Aerosolâ€UVâ€Assisted MOCVD. Chemical Vapor Deposition, 2015, 21, 26-32.	1.3	4
58	Exploring the optical properties of Vernier phase yttrium oxyfluoride thin films grown by pulsed liquid injection MOCVD. Dalton Transactions, 2018, 47, 2655-2661.	3.3	4
59	Er, Yb, and Er, Yb (CO-)doped yttria thin films, deposited by an aerosol assisted MO-CVD process. European Physical Journal Special Topics, 1999, 09, Pr8-583-Pr8-588.	0.2	4
60	Elaboration par le procÃ©dÃ© pyrosol de couches minces texturÃ©es de ZnO pour la rÃ©alisation de microcapteurs. Journal De Physique III, 1994, 4, 1243-1251.	0.3	3
61	Effect of humidity and UV-assistance on the preparation of erbium doped alumina by aerosol MOCVD process. Applied Surface Science, 2012, 258, 2591-2596.	6.1	3
62	Preparation and microstructural properties of erbium doped aluminaâ€“yttria oxide thin films deposited by aerosol MOCVD. Journal of Luminescence, 2013, 142, 52-56.	3.1	3
63	The quest towards epitaxial BaMgF4 thin films: exploring MOCVD as a chemical scalable approach for the deposition of complex metal fluoride films. Dalton Transactions, 2016, 45, 17833-17842.	3.3	3
64	Optimized Stoichiometry for CuCrO2 Thin Films as Hole Transparent Layer in PBDD4T-2F:PC70BM Organic Solar Cells. Nanomaterials, 2021, 11, 2109.	4.1	3
65	Study of the growth conditions and characterization of CaCu2Ox and SrCu2Ox thin films. Surface and Coatings Technology, 2007, 201, 9395-9399.	4.8	2
66	Growth rate induced high efficient light trapping/photon conversion ZnO:Nd 3+ nanodisk shaped thin films deposited by AACVD process. Journal of Alloys and Compounds, 2015, 651, 756-763.	5.5	2
67	The Role of Humidity in Tuning the Texture and Electrical Properties of Cu₂O Thin Films Deposited via Aerosolâ€Assisted CVD. Advanced Materials Interfaces, 2019, 6, 1801364.	3.7	2
68	Couches minces de grenat substituÃ© dÃ©posÃ©es par le procÃ©dÃ© pyrosol pour l'enregistrement magnÃ©to-optique. European Physical Journal Special Topics, 1992, 02, C3-29-C3-33.	0.2	2
69	Deposition by an aerosol assisted MOCVD process of Eu or Er doped Y2O3-P2O5 thin films. European Physical Journal Special Topics, 2001, 11, Pr3-653-Pr3-660.	0.2	1
70	Inorganic color filters by MOCVD for CMOS imager and colorimetry. Proceedings of SPIE, 2008, , .	0.8	1
71	Thulium and ytterbium-doped titania thin films deposited by MOCVD. Energy Procedia, 2011, 10, 192-196.	1.8	1
72	An RBS study of thin PLD and MOCVD strontium copper oxide layers. Thin Solid Films, 2008, 516, 8136-8140.	1.8	0